



EL 465779878
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

1310
9/5/01
Harrison

Application Serial No. 09/212,726
Filing Date December 15, 1998
Inventor Klaus Florian Schuegraf
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner E. Kielin
Attorney's Docket No. MI22-1098
Title: Semiconductor Processing Methods of Chemical Vapor Depositing
SiO2 on a Substrate

RESPONSE TO FEBRUARY 28, 2001 OFFICE ACTION

To: Assistant Commissioner for Patents
Washington, D.C. 20231

From: Bernard Berman (Tel. 509-624-4276; Fax 509-838-3424)
Wells, St. John, Roberts, Gregory & Matkin P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

Sir:

Responsive to the Office Action dated February 28, 2001, Applicant respectfully requests reconsideration of the above-referenced application in view of the remarks that follow.

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